

What is claimed is:

1 1. An apparatus which controls tilting of a tilt mirror,
2 said apparatus comprising:
3 a control signal producing unit which produces a control
4 signal, for feed-forward controlling of the tilting of said
5 mirror, based on a parameter that determines a target tilt
6 angle of said tilt mirror;
7 a digital filter that removes a resonance frequency
8 component, which is caused by movement of said tilt mirror
9 into a desired angle, in said control signal, which is produced
10 by said control signal producing unit; and
11 a square root calculating unit that performs digital
12 square-root calculation so as to compensate for non-linearity
13 of said control signal, from which said resonance frequency
14 component has been removed.

1 2. An apparatus as set forth in claim 1, wherein said
2 control signal producing unit includes:
3 a parameter input unit which inputs said parameter as
4 said target tilt angle and driving property information of
5 said tilt mirror; and
6 an arithmetic operation unit which obtains said control
7 signal by arithmetic operation based on said target tilt
8 angle and said driving property information of said tilt
9 mirror, both of which are input by said parameter input unit.

1 3. An apparatus as set forth in claim 2, said apparatus
2 further comprising:

3 a plurality of electrodes arranged for each said tilt
4 mirror; and

5 a switch that selects, based on said control signal,
6 one of said plurality of electrodes to which said control
7 signal is provided.

1 4. An apparatus as set forth in claim 2, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 5. An apparatus as set forth in claim 3, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 6. An apparatus as set forth in claim 1, said apparatus
2 further comprising:

3 a plurality of electrodes arranged for each said tilt
4 mirror; and

5 a switch that selects, based on said control signal,
6 one of said plurality of electrodes to which said control
7 signal is provided.

1 7. An apparatus as set forth in claim 6, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 8. An apparatus as set forth in claim 1, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 9. A method for controlling tilting of a tilt mirror,
2 said method comprising the steps of:
3 producing a control signal, for controlling the tilting
4 of said mirror, based on a parameter which determines a target
5 tilt angle of said tilt mirror;
6 removing a resonance frequency component, which is
7 caused by movement of said tilt mirror into a desired angle,
8 from said control signal by a digital filter; and
9 performing digital square-root calculation so as to
10 compensate for non-linearity of said control signal.

1 10. An apparatus which controls tilting of a tilt mirror
2 which is controlled by electrostatic attraction, said
3 apparatus comprising:
4 a control signal producing unit which produces a control
5 signal, for controlling the tilting of said mirror, based
6 on a parameter that determines a target tilt angle of said
7 tilt mirror; and
8 a non-linearity compensation calculating unit which
9 performs voltage approximate calculation so as to compensate
10 for non-linearity, in said control signal obtained by said
11 control signal producing unit, of said tilt angle against
12 electrostatic capacity of said tilt mirror, a driving signal

13 for driving said tilt mirror being thereby produced.

1 11. An apparatus as set forth in claim 10, wherein said
2 non-linearity compensation calculating unit includes a
3 non-linearity compensation calculating table which stores,
4 as result of such voltage approximate calculation, voltage
5 V_d of said driving signal given by:

6
7
$$V_d = \sqrt{\frac{\theta_{\max}}{V_{C_{\max}}} V_c} / \alpha \left(\frac{\theta_{\max}}{V_{C_{\max}}} V_c \right) \quad \dots \quad (C-4)$$

8
9 where V_c represents a voltage of said control signal; $V_{C_{\max}}$
10 represents a maximal value of the voltage of said control
11 signal; θ_{\max} is a maximal value of said tilt angle.

1 12. An apparatus as set forth in claim 11, wherein said
2 non-linearity compensation calculating unit further
3 includes:

4 a gain information storing unit which stores gain
5 information, one information item for each of said plurality
6 of tilt mirrors having an identical construction, each said
7 information item compensating for a spring constant error
8 of a corresponding one of said plurality tilt mirrors; and
9 a gain adjusting unit which adjusts an output gain of
10 said non-linearity compensation calculating table based on
11 said gain information stored in said gain information storing
12 unit.

1 13. An apparatus as set forth in claim 12, wherein said
2 control signal producing unit has a digital filter which
3 removes, from the control signal, a resonance frequency
4 component caused by movement of said tilt mirror into a desired
5 angle.

1 14. An apparatus as set forth in claim 12, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 15. An apparatus as set forth in claim 13, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 16. An apparatus as set forth in claim 11, wherein said
2 control signal producing unit has a digital filter which
3 removes, from the control signal, a resonance frequency
4 component caused by movement of said tilt mirror into a desired
5 angle.

1 17. An apparatus as set forth in claim 16, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 18. An apparatus as set forth in claim 11, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 19. An apparatus as set forth in claim 10, wherein said
2 control signal producing unit has a digital filter that
3 removes, from the control signal, a resonance frequency
4 component, which is caused by movement of said tilt mirror
5 into a desired angle.

1 20. An apparatus as set forth in claim 19, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 21. An apparatus as set forth in claim 10, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 22. An apparatus as set forth in claim 21, such MEMS
2 tilt mirror having a comb-shaped electrode to receive said
3 driving signal.

1 23. A method for controlling tilting of a tilt mirror
2 which is controlled by electrostatic attraction, said method
3 comprising the steps of:

4 producing a control signal, for controlling the tilting
5 of said mirror, based on a parameter which determines a target
6 tilt angle of said tilt mirror; and

7 performing voltage approximate calculation so as to
8 compensate for non-linearity, in said control signal obtained
9 by said control signal producing unit, of said tilt angle

10 against electrostatic capacity of said tilt mirror, a driving
11 signal for driving said tilt mirror being thereby produced.

1 24. An apparatus which controls tilting of a tilt mirror
2 which is controlled by electrostatic attraction, said
3 apparatus comprising:

4 a control signal producing unit which produces a control
5 signal for controlling the tilting of said mirror; and

6 a pulse waveform compensation unit which controls and
7 compensates for a pulse waveform that appears in initial
8 part of the control signal, which is produced by said control
9 signal producing unit.

1 25. An apparatus as set forth in claim 24, further
2 comprising a band elimination filter, disposed between said
3 control signal producing unit and said pulse waveform
4 compensation unit, which filter removes, from the control
5 signal, a resonance frequency component caused by movement
6 of said tilt mirror into a desired angle and produces a step
7 signal,

8 said pulse waveform compensation unit controlling only
9 the pulse waveform which appears in the initial part of the
10 step signal.

1 26. An apparatus as set forth in claim 25, wherein said
2 band elimination filter is a digital filter.

1 27. An apparatus as set forth in claim 24, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 28. An apparatus as set forth in claim 25, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 29. An apparatus as set forth in claim 26, wherein said
2 tilt mirror is an MEMS (Micro Electro Mechanical Systems)
3 mirror.

1 30. A method for controlling tilting of a tilt mirror,
2 said method comprising the steps of:
3 producing a control signal for controlling the tilting
4 of said mirror; and
5 controlling and compensating for a pulse waveform
6 appearing in initial part of the control signal which is
7 produced by said control signal producing unit.